

FIG. 1

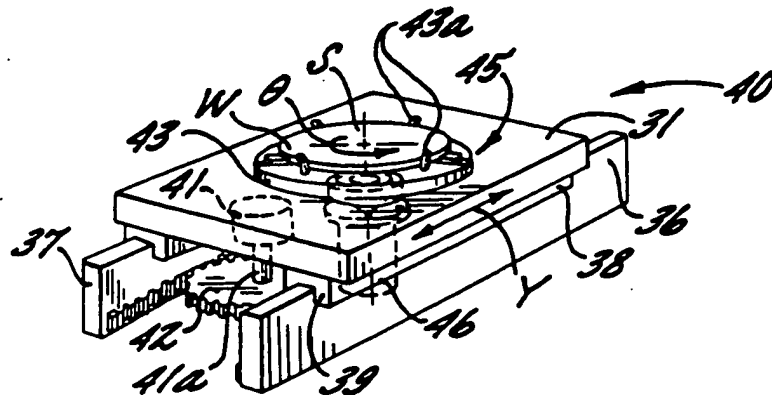


FIG. 2

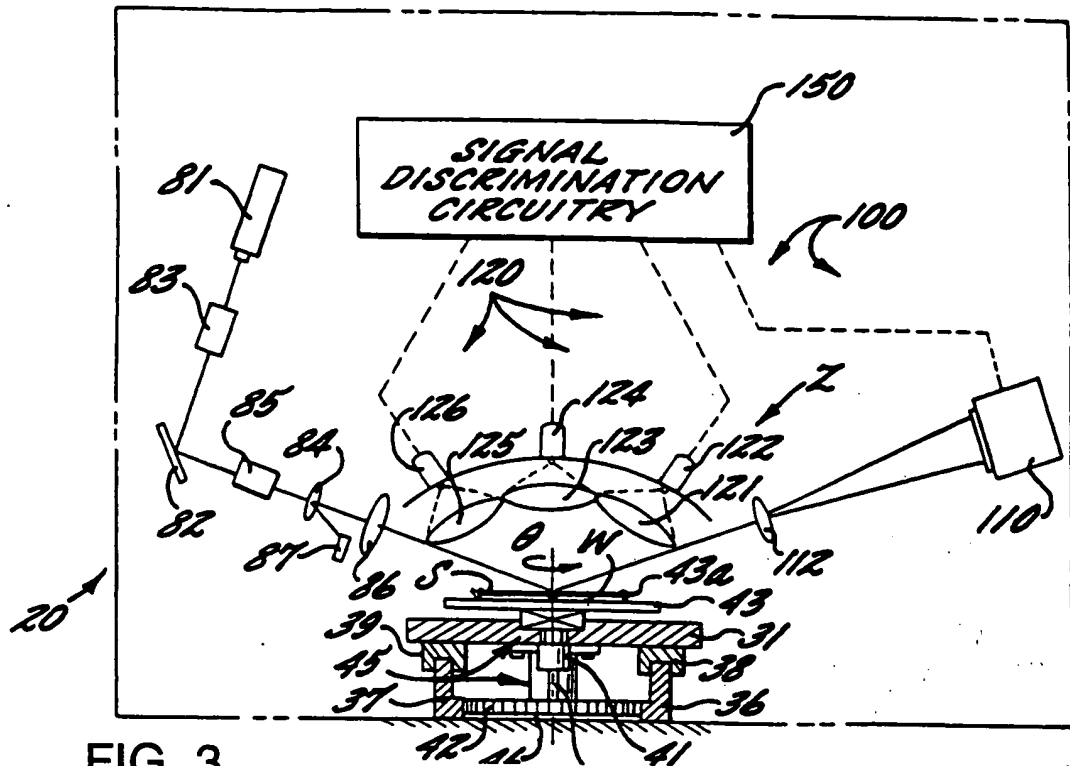


FIG. 3

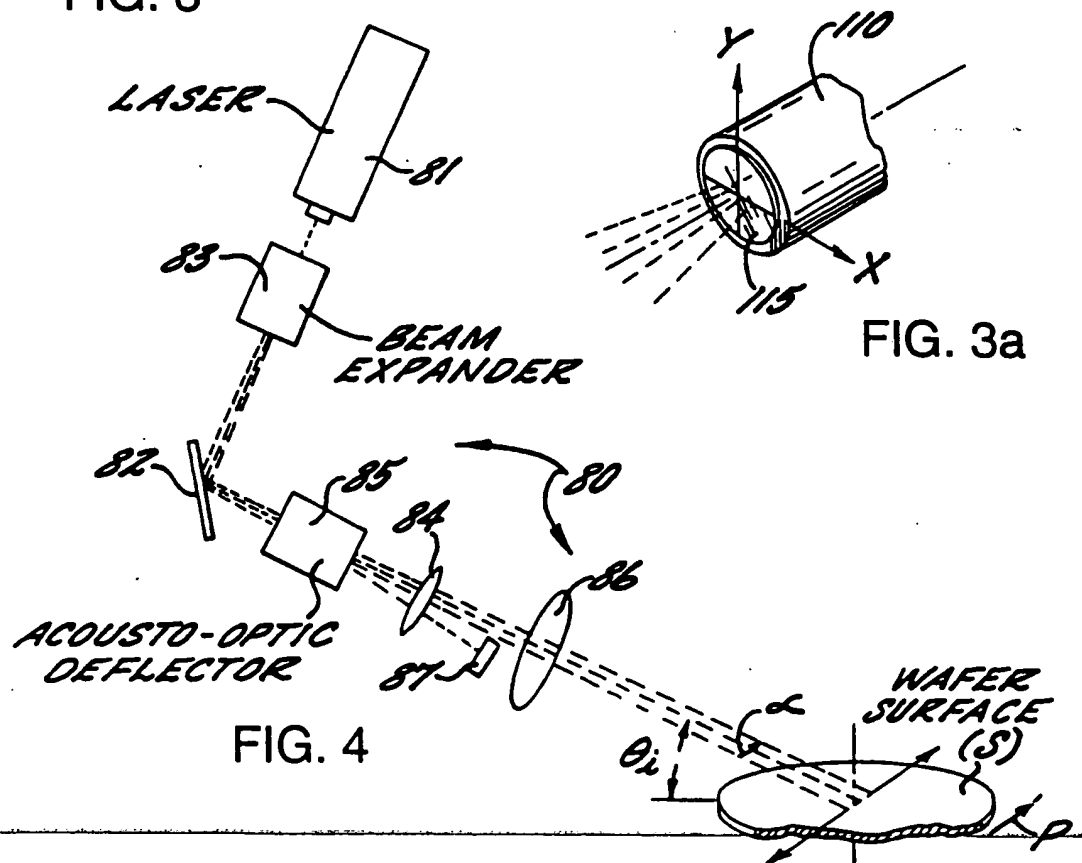


FIG. 4

FIG. 3a

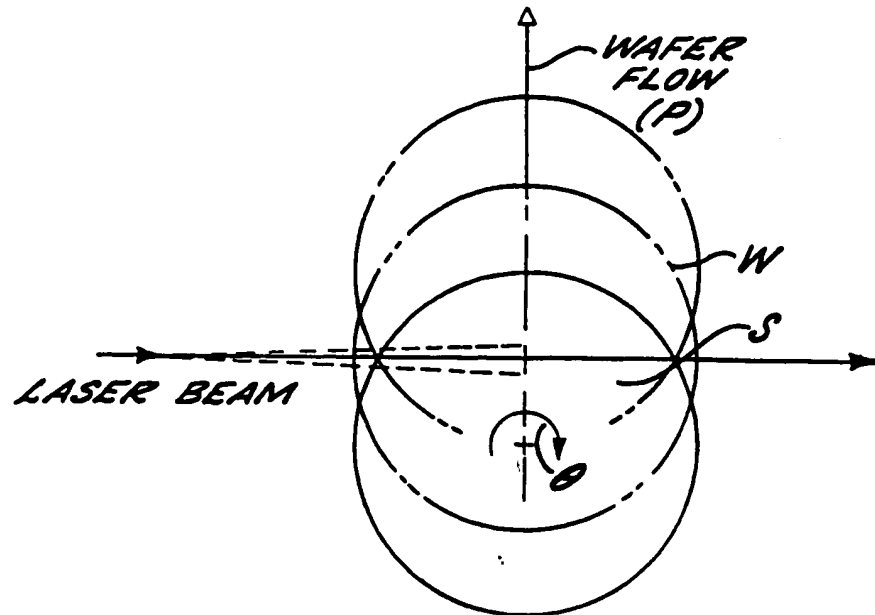


FIG. 5

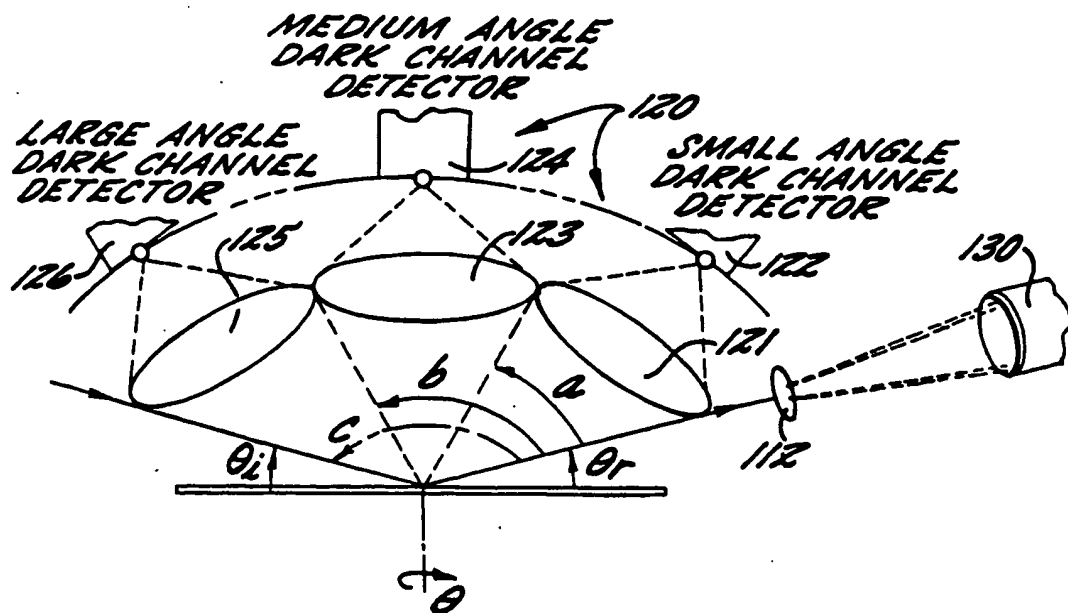


FIG. 6

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AND PARTICLES

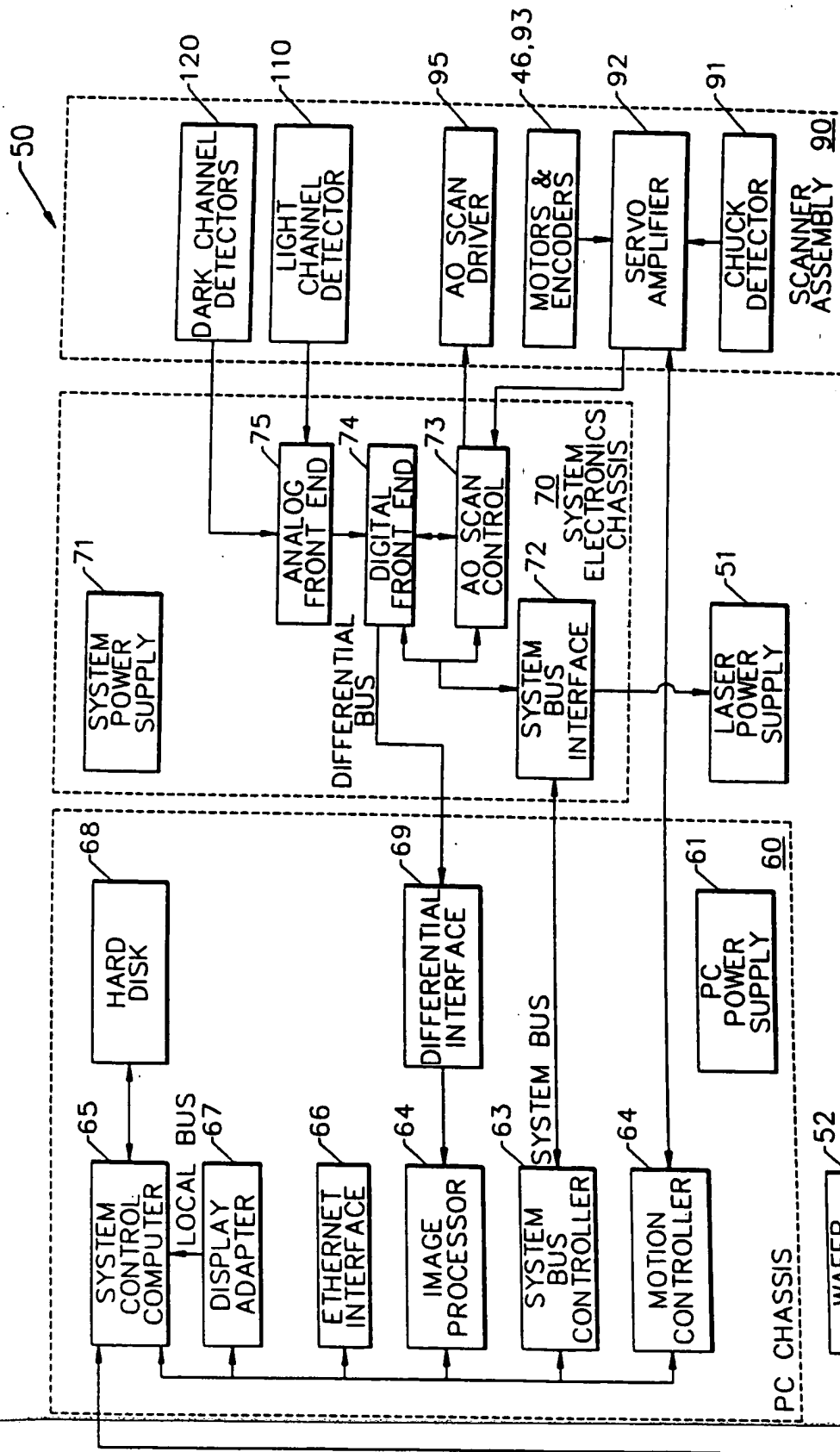


FIG. 7

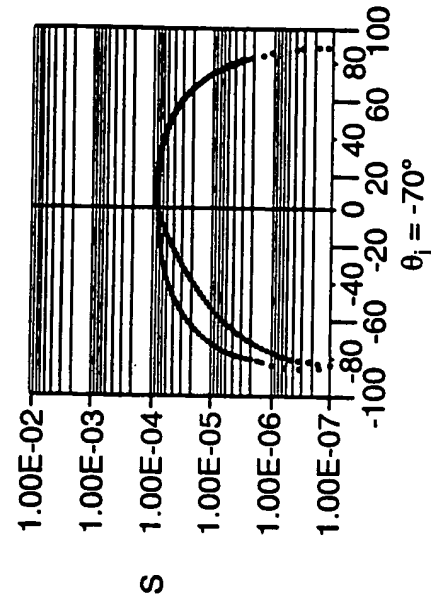


FIG. 8A

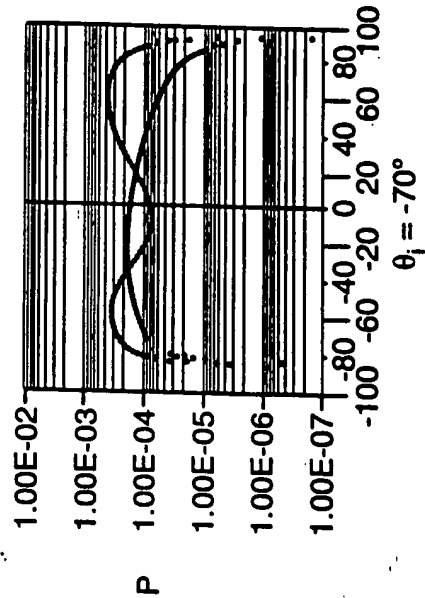


FIG. 8B

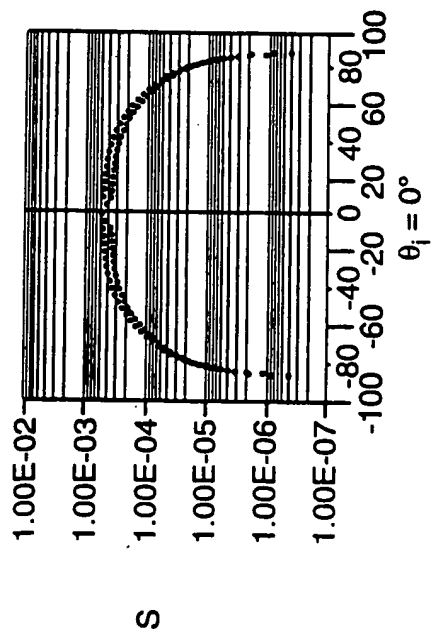


FIG. 8C

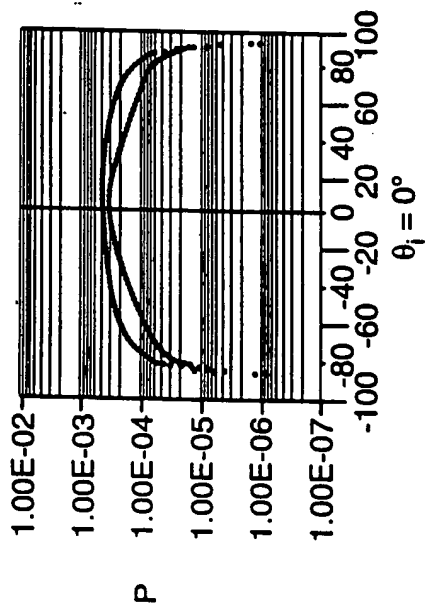


FIG. 8D

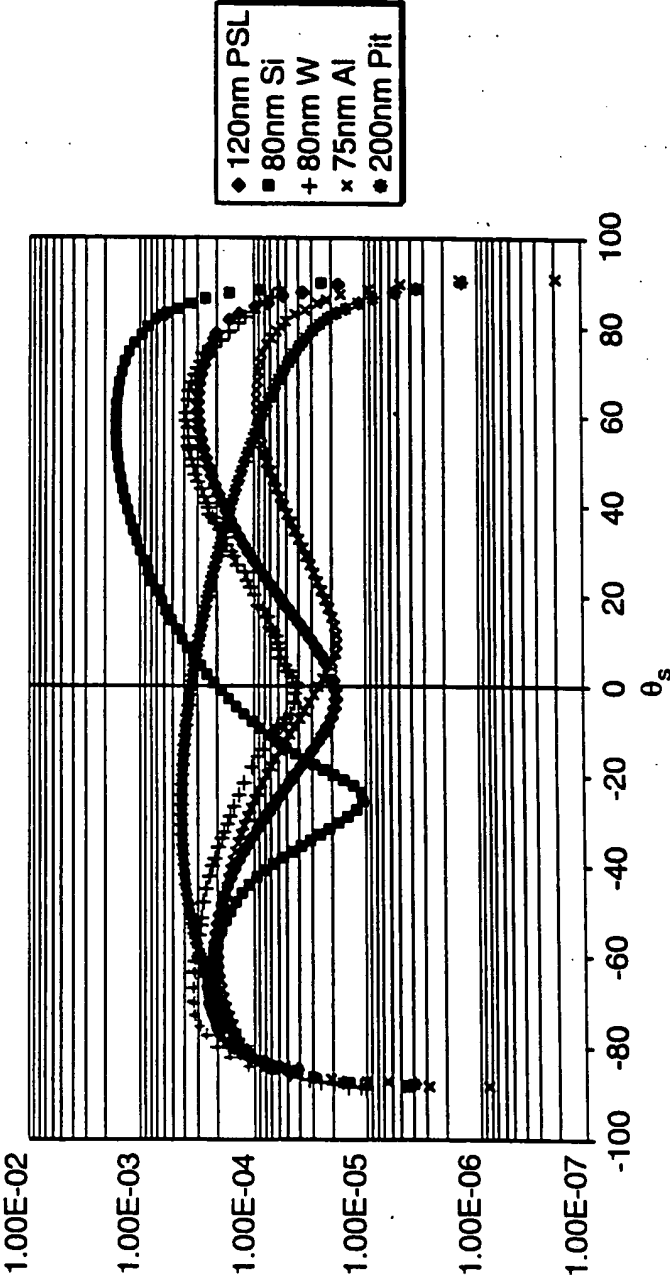


FIG. 9

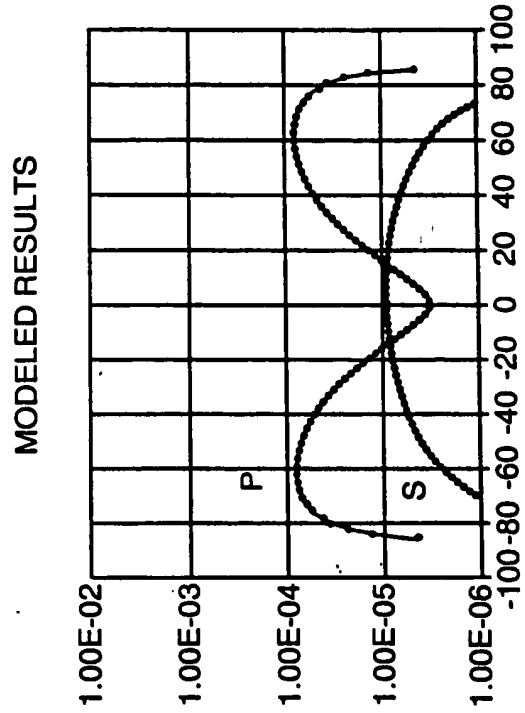


FIG. 10B

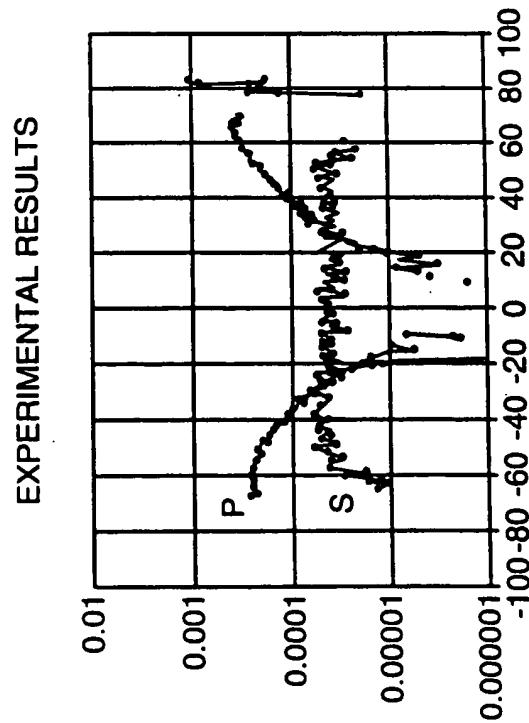


FIG. 10A

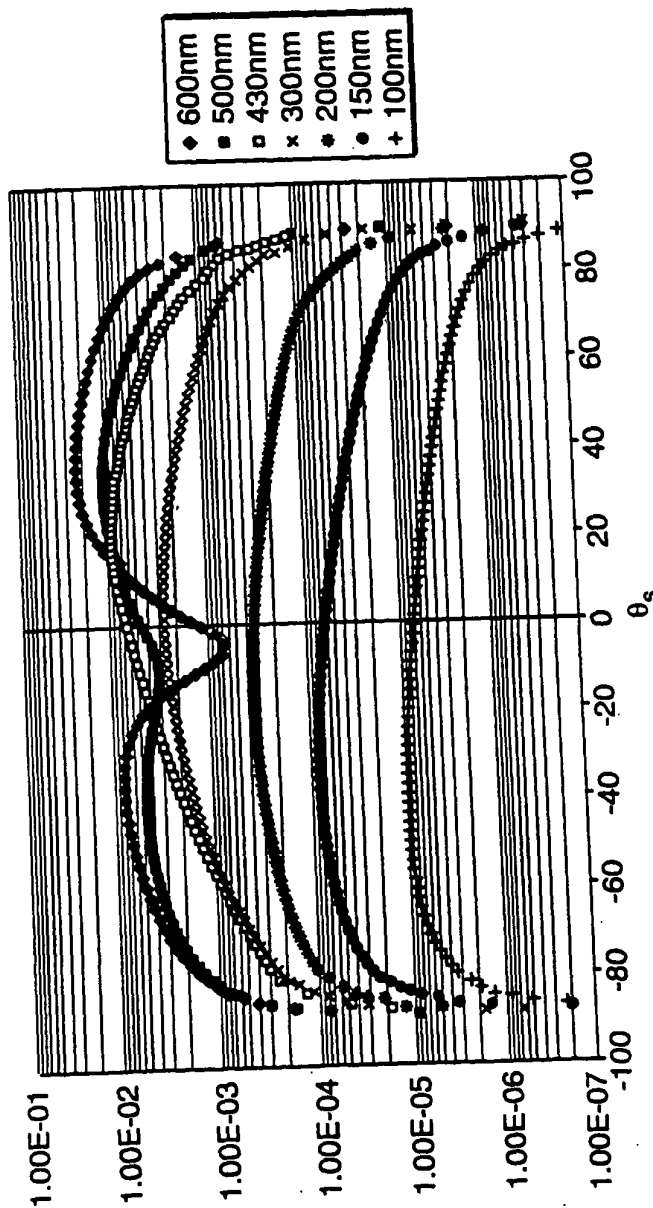


FIG. 11

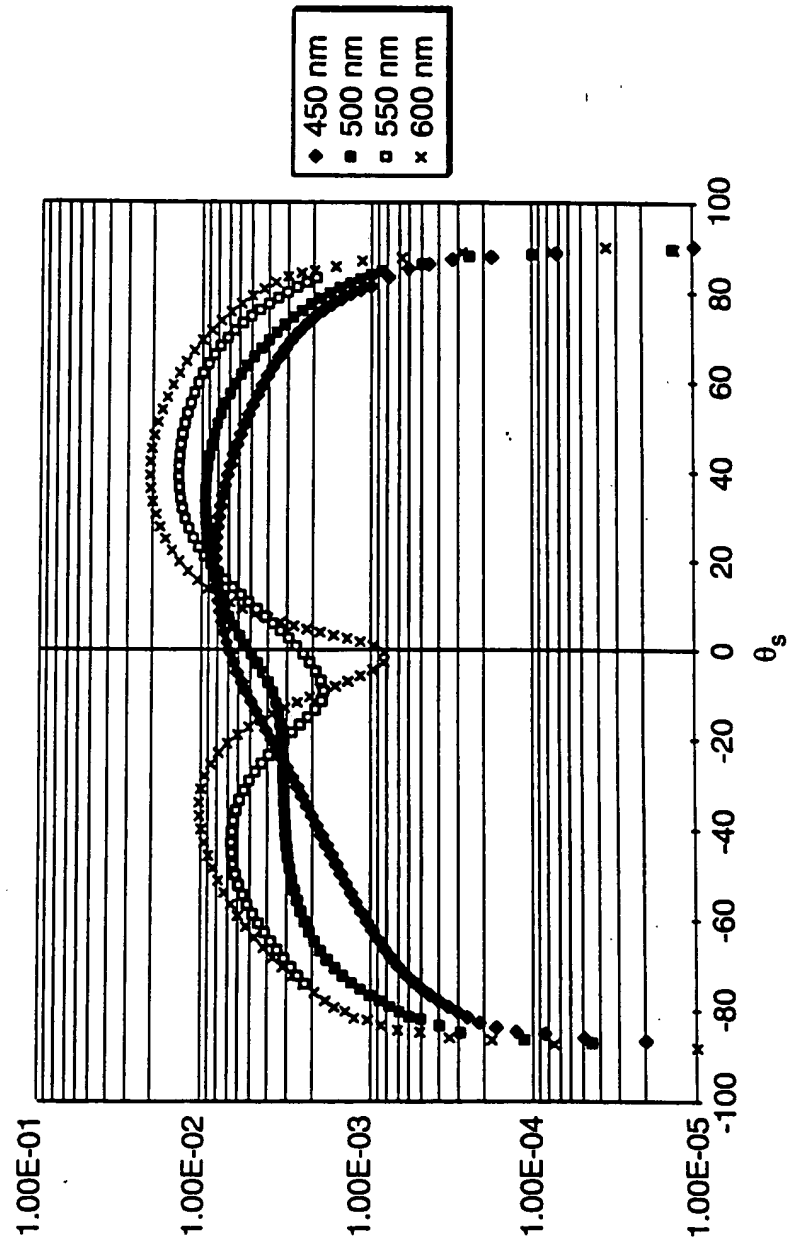


FIG. 12

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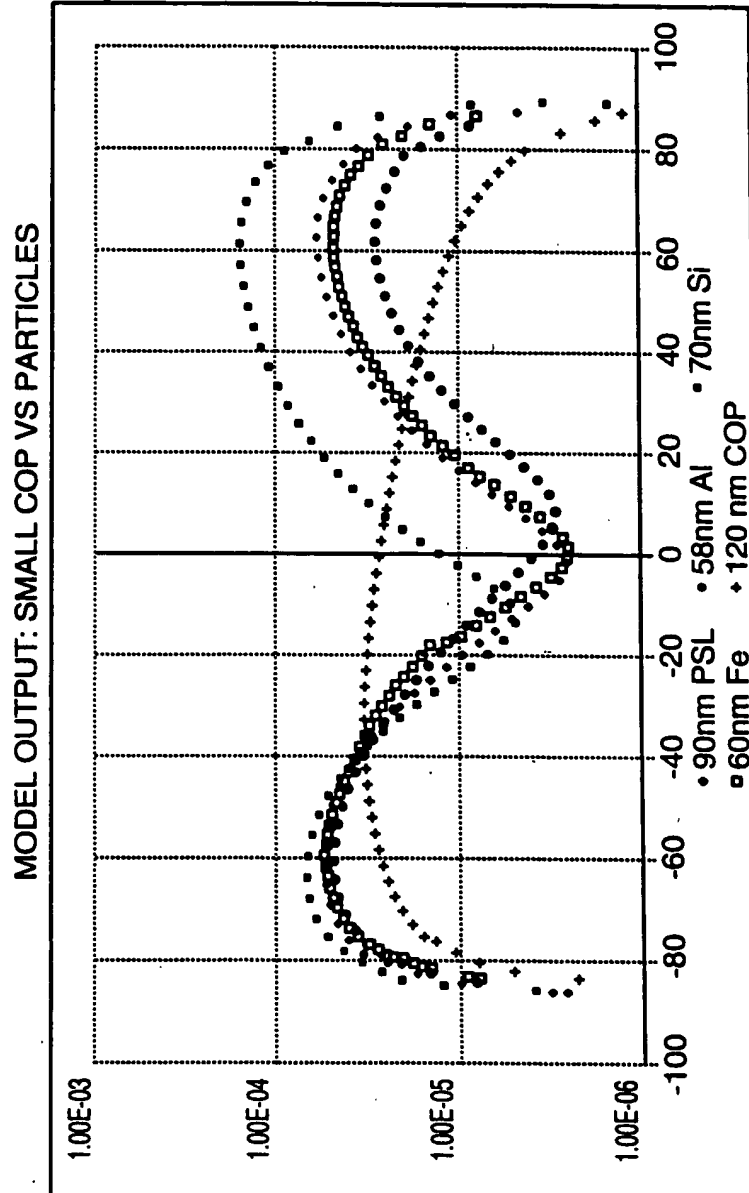
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AND PARTICLES

FIG. 13

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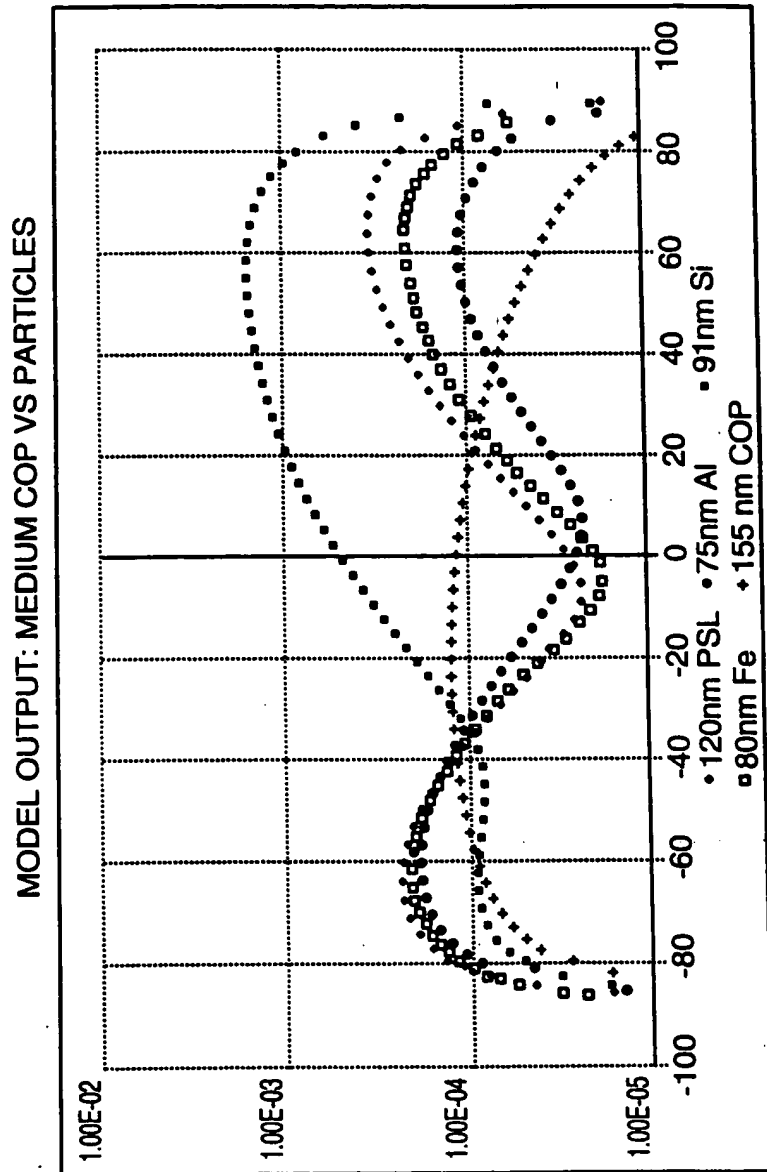
WAFER INSPECTION SYSTEM FOR DISTINGUISHING PITS
AND PARTICLES

FIG. 14

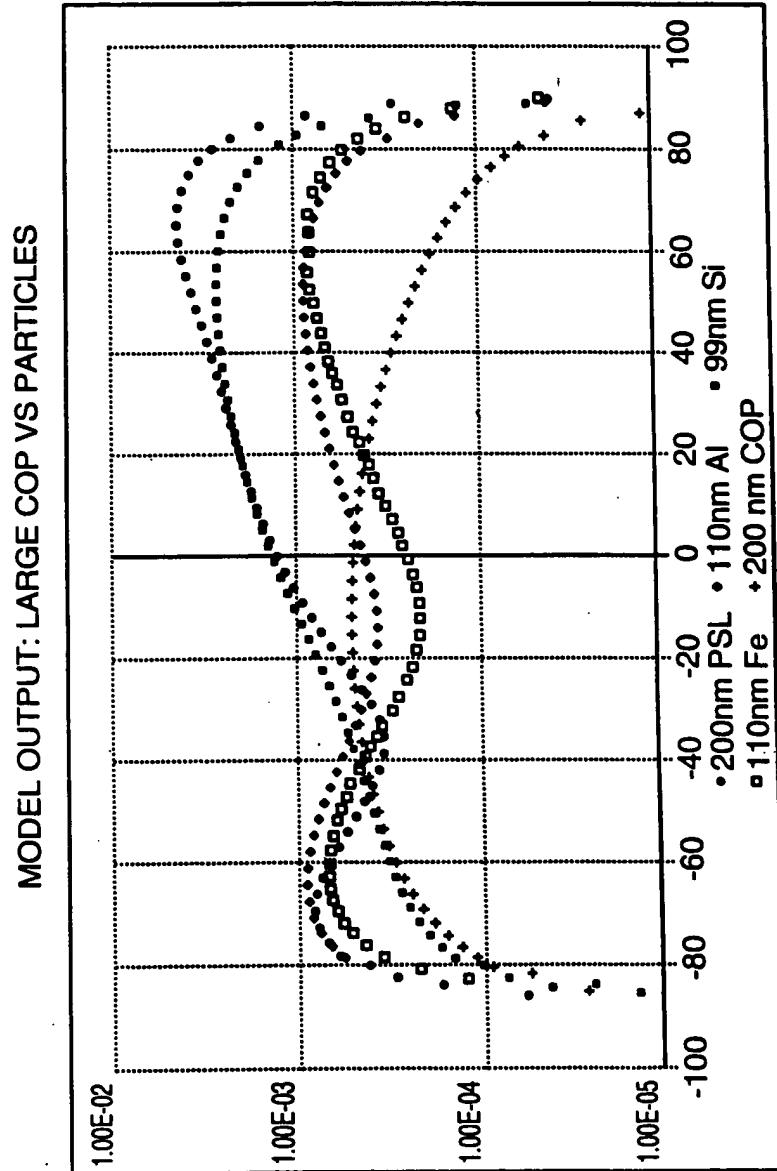


FIG. 15

COP ALGORITHM

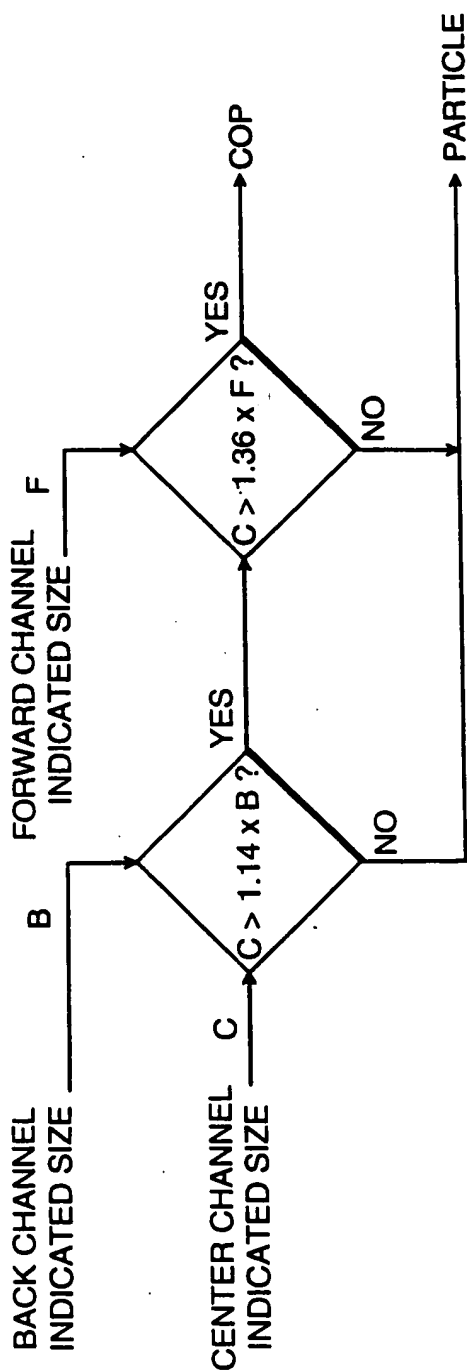


FIG. 16

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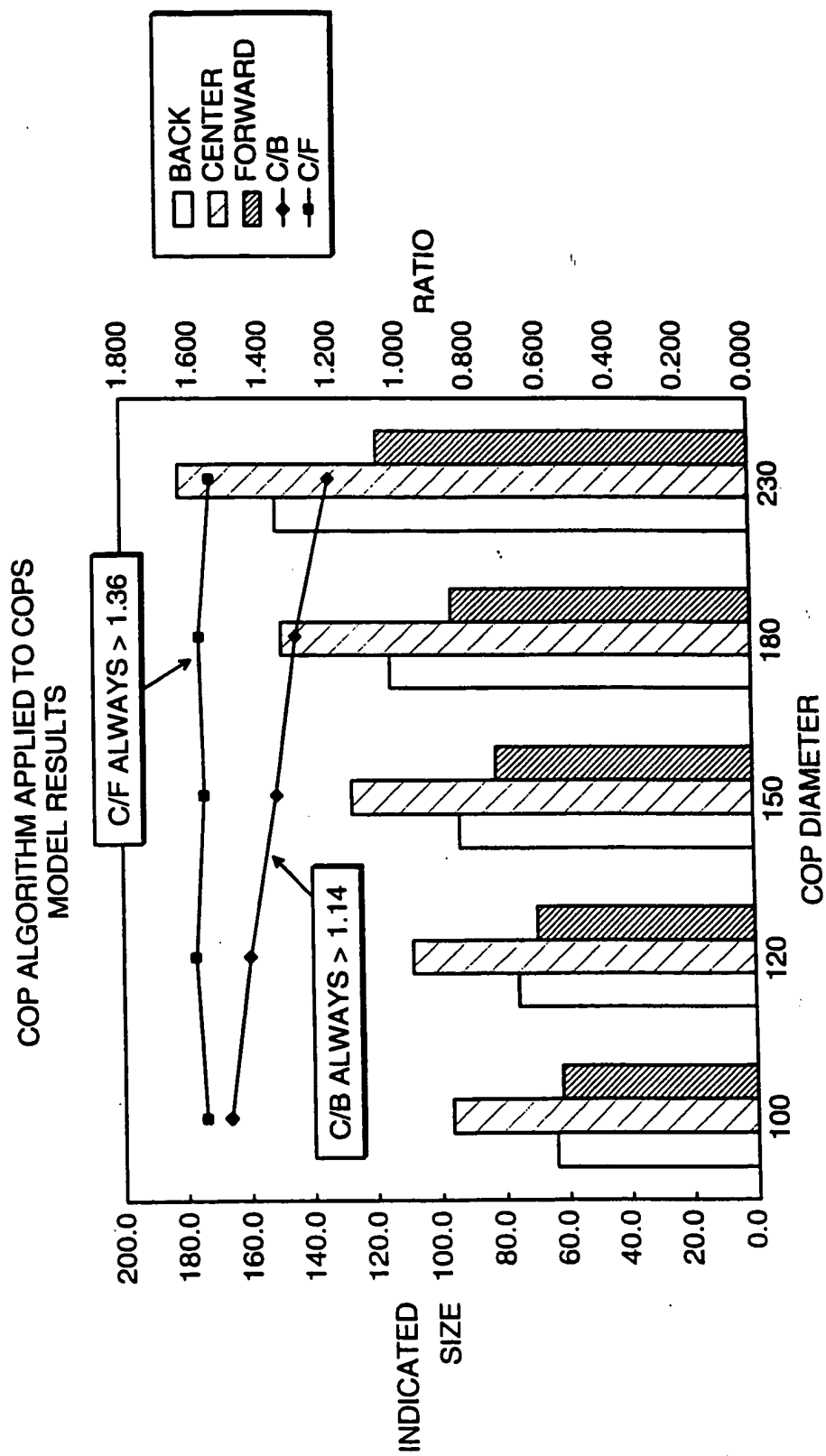


FIG. 17

Applicant(s): Michael E. Fossey et al.

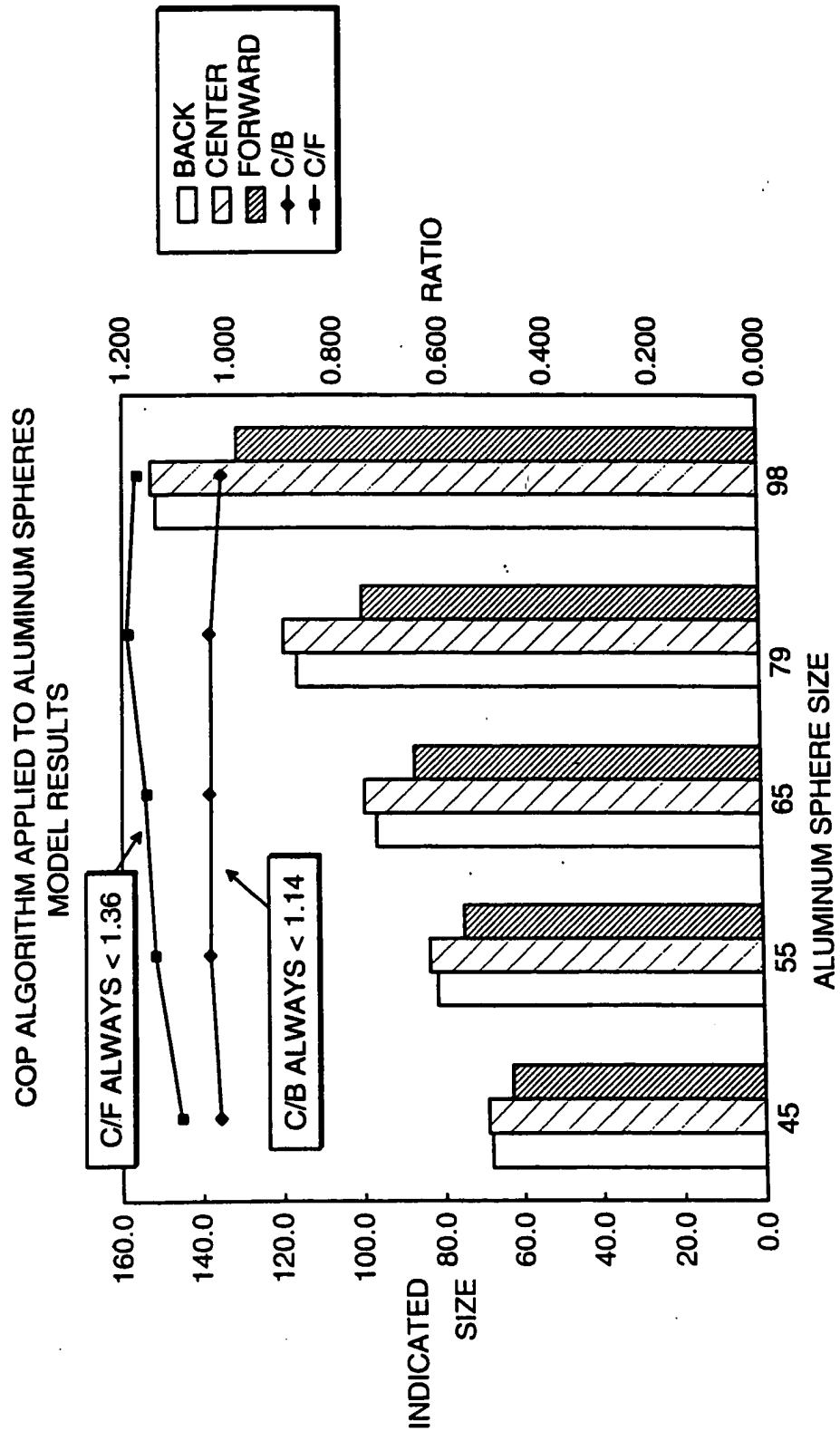
WAFER INSPECTION SYSTEM FOR DISTINGUISHING PITS
AND PARTICLES

FIG. 18

AWIS PARTICLE MAP OF CLEAN CZ WAFER

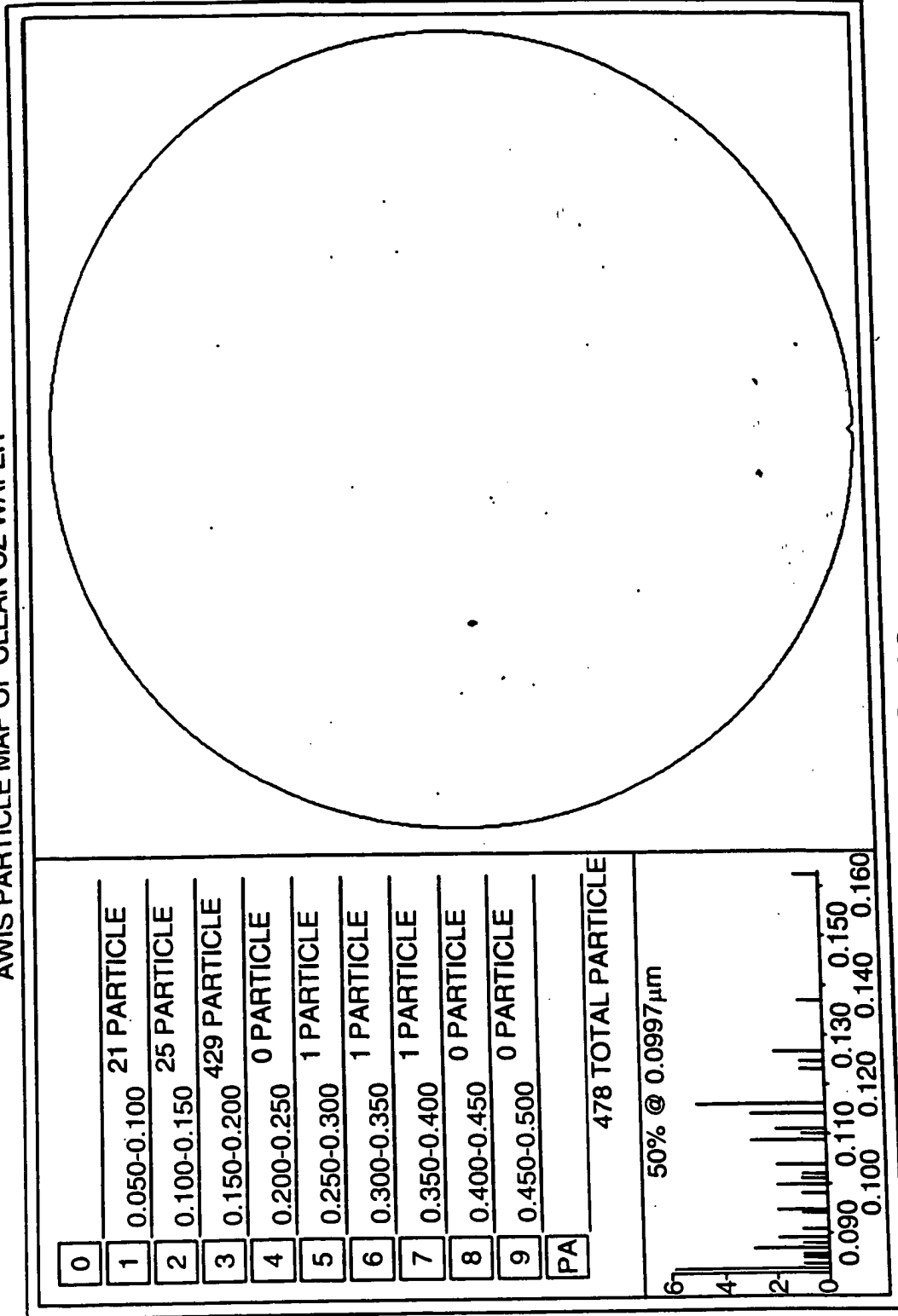


FIG. 19

AWIS COP MAP OF CLEAN CZ WAFER

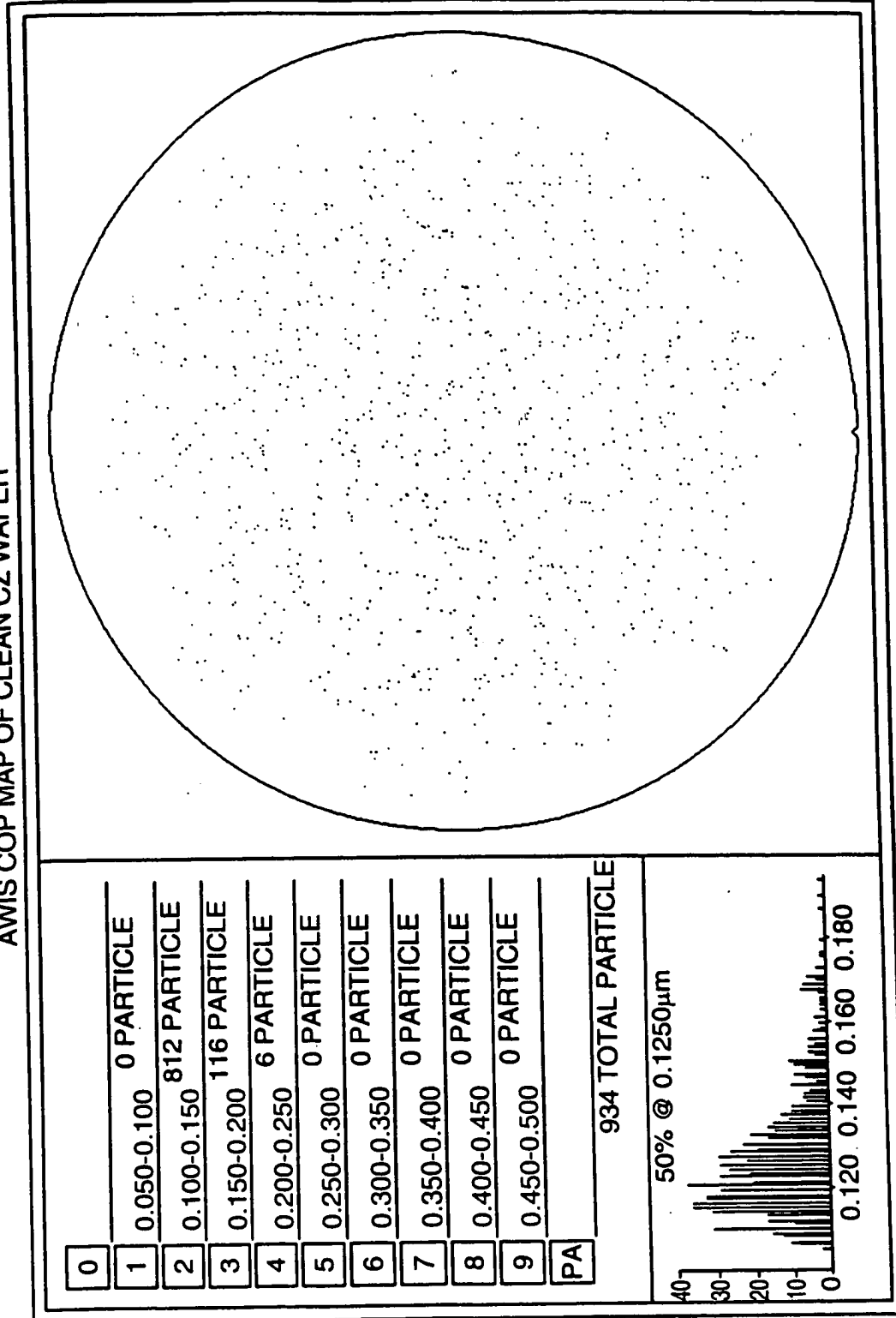


FIG. 20

AWIS PARTICLE MAP OF CZ WAFER WITH 117nm, 136nm & 157nm

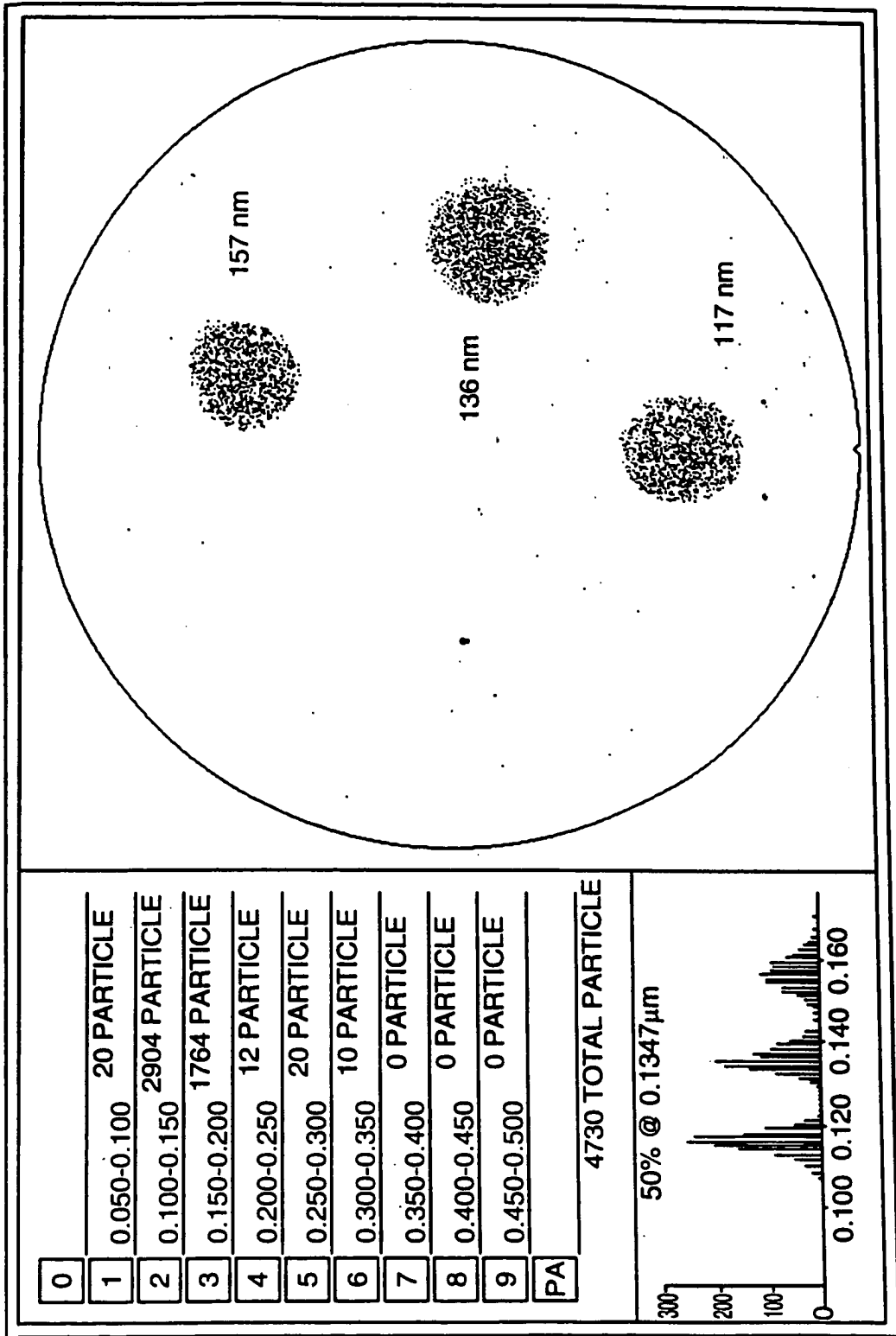


FIG. 21

AWIS COP MAP OF CZ WAFER WITH 117nm, 136nm & 157nm

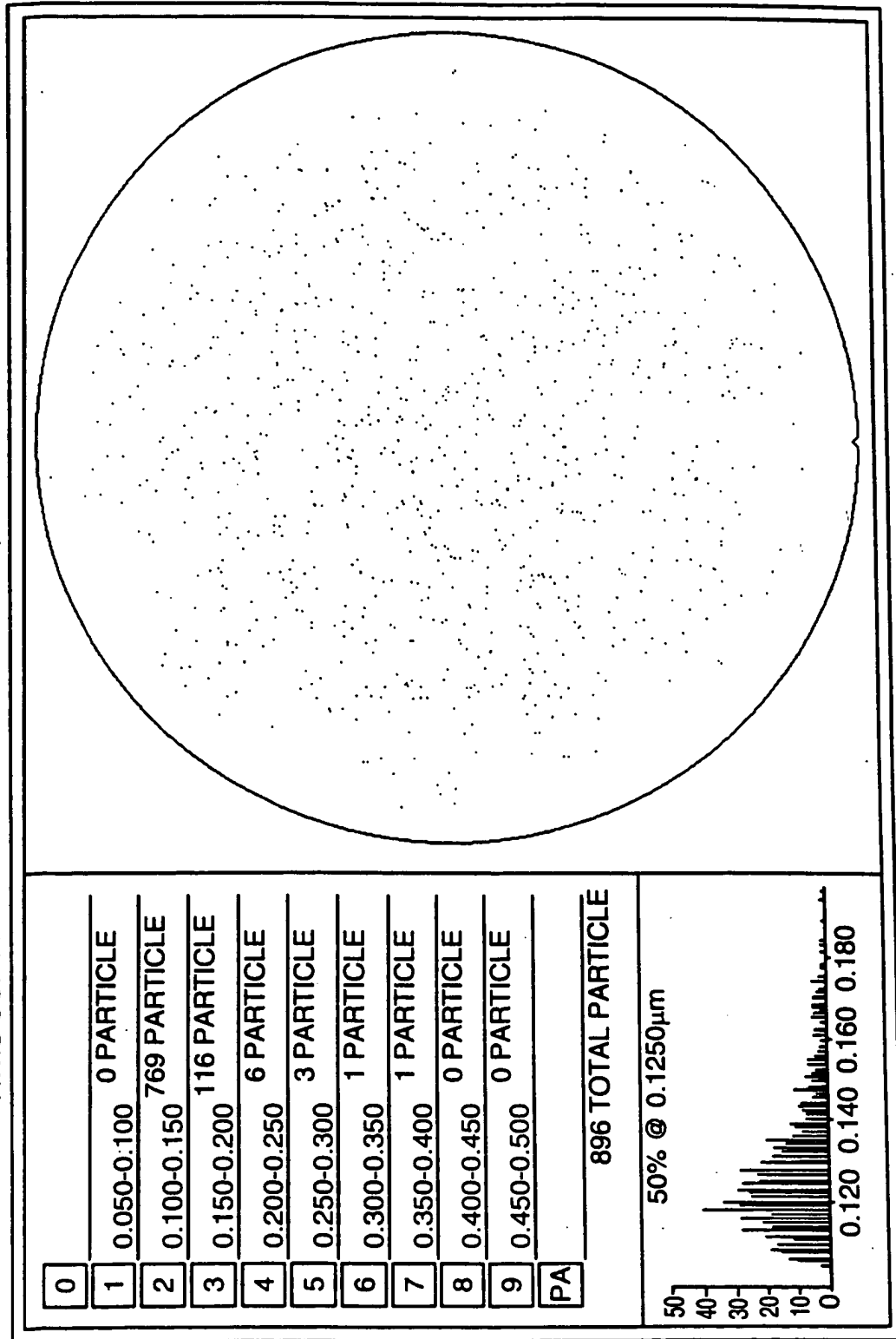


FIG. 22